



WEGU-DEVICE, INC.

INDUSTRIAL SENSORS & PROCESS AUTOMATION

ATF6 information short version



光技術をサポートする

株式会社オプトサイエンス

<http://www.optoscience.com>

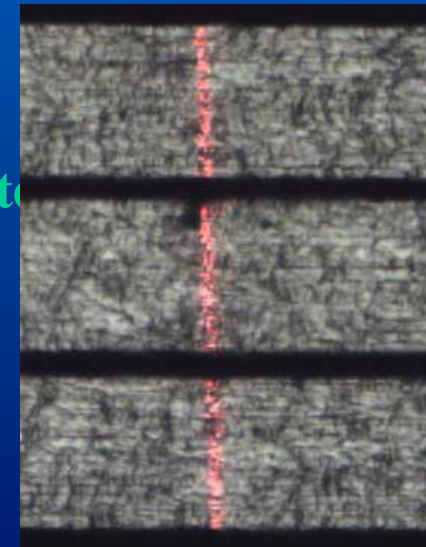
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ATF-6 General Functionality

- *ATF-6* is a latest member of the ATF sensors family
- Designed to function accurately on very busy patterns down to diffusing surfaces such as patterned silicon wafers
- One-to-one compatible with ATF-5 and ATF-4
- Main features:
 - Operates at 1 kHz update rate (3 fold faster than ATF-5)
 - Surface recognition
 - C/M mode
 - Profilometer
 - Significantly reduced laser intensity

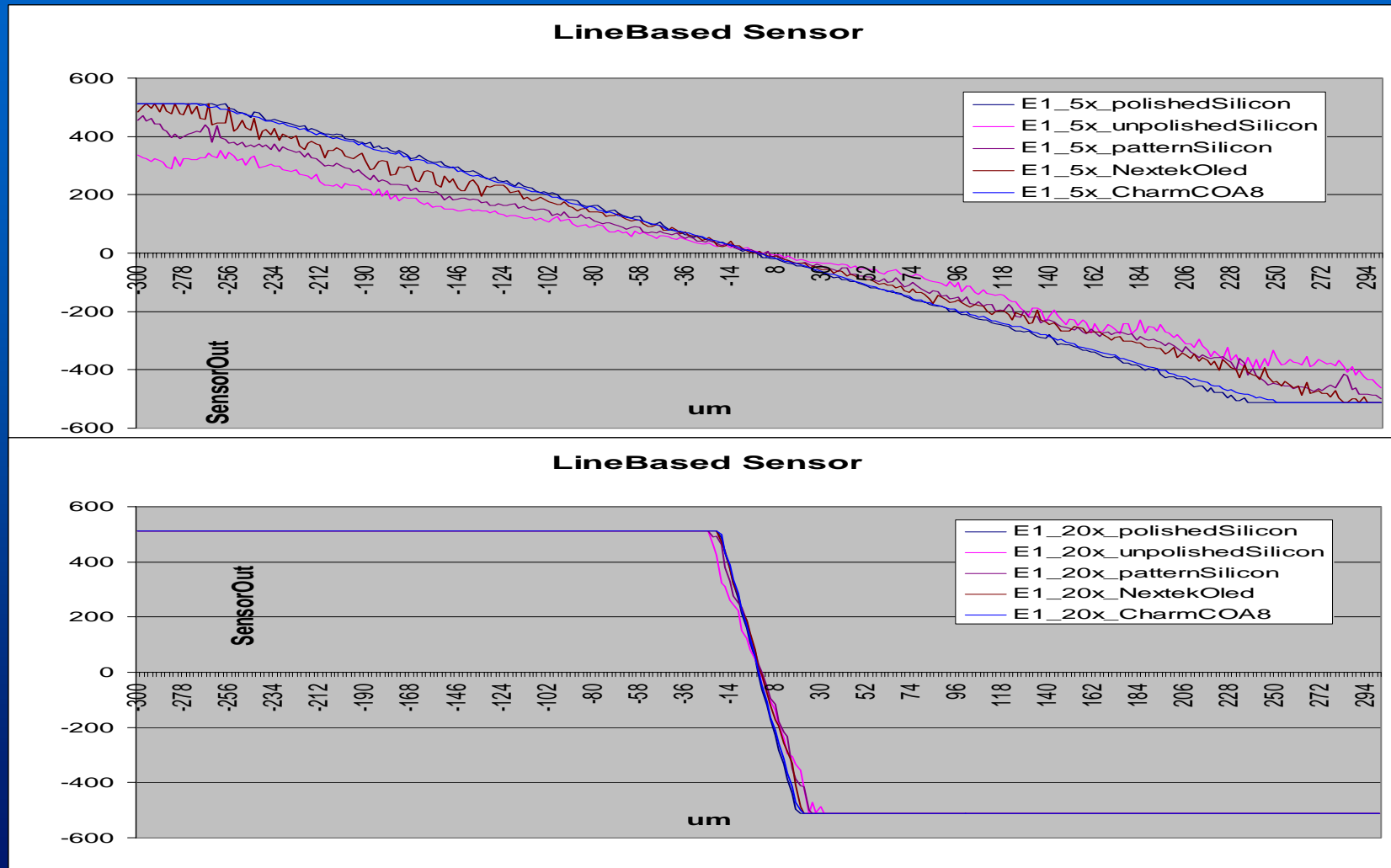
ATF-6 Principle of Operation

- Operates on the principle of *Monocular Triangulation*TM
- Features redesigned optics:
 - Instead of array of dots (ATF-5), ATF-6 projects a line segment
- High accuracy is assured by means of DIP:
 - The “sparse” bad spots are eliminated from the layers and only good segments are integrated into the measurement
 - On diffusing or semi diffusing surfaces sensor focusing position
 - Can be offset by S/W to focus above or below



Stainless lithography mask

ATF-6 Performance



ATF-6 Domains of Application

- *ATF-6* sensor is primarily designed for AOI equipment operating on:
 - Patterned silicon wafer
 - Photo-lithography masks (semi-con type)
 - OLEDs
- *ATF-6* sensor may replace ATF-5 for TFT applications, if the TFT patterns will continue to grow in their complexity